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Semiconductor devices - Micro-electromechanical devices - Part 22: Electromechanical tensile test method for conductive thin films on flexible substrates

Táto norma obsahuje anglickú verziu európskej normy.
This standard includes the English version of the European Standard.

Táto norma bola oznámená vo Vestníku ÚNMS SR č. 01/15

Obsahuje: EN 62047-22:2014, IEC 62047-22:2014

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English Version

**Semiconductor devices - Micro-electromechanical devices -
Part 22: Electromechanical tensile test method for conductive
thin films on flexible substrates
(IEC 62047-22:2014)**

Dispositifs à semiconducteurs - Dispositifs
microélectromécaniques -
Partie 22: Méthode d'essai de traction électromécanique
pour les couches minces conductrices sur des substrats
souples
(CEI 62047-22:2014)

Halbleiterbauelemente - Bauelemente der
Mikrosystemtechnik -
Teil 22: Elektromechanisches Zug-Prüfverfahren für
leitfähige Dünnschichten auf flexiblen Substraten
(IEC 62047-22:2014)

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Comité Européen de Normalisation Electrotechnique
Europäisches Komitee für Elektrotechnische Normung

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Foreword

The text of document 47F/186/FDIS, future edition 1 of IEC 62047-22, prepared by SC 47F "Microelectromechanical systems" of IEC/TC 47 "Semiconductor devices" was submitted to the IEC-CENELEC parallel vote and approved by CENELEC as EN 62047-22:2014.

The following dates are fixed:

- latest date by which the document has to be implemented at national level by publication of an identical national standard or by endorsement (dop) 2015-04-24
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NOTE 1 When an International Publication has been modified by common modifications, indicated by (mod), the relevant EN/HD applies.

NOTE 2 Up-to-date information on the latest versions of the European Standards listed in this annex is available here: www.cenelec.eu

<u>Publication</u>	<u>Year</u>	<u>Title</u>	<u>EN/HD</u>	<u>Year</u>
IEC 62047-2	2006	Semiconductor devices - Micro-electromechanical devices - Part 2: Tensile testing method of thin film materials	EN 62047-2	2006
IEC 62047-3	2006	Semiconductor devices - Micro-electromechanical devices - Part 3: Thin film standard test piece for tensile testing	EN 62047-3	2006
IEC 62047-8	2011	Semiconductor devices - Micro-electromechanical devices - Part 8: Strip bending test method for tensile property measurement of thin films	EN 62047-8	2011
ISO 527-3	1995	Plastics - Determination of tensile properties - Part-3: Test conditions for films and sheets	EN ISO 527-3	1995



INTERNATIONAL STANDARD

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**Semiconductor devices – Micro-electromechanical devices –
Part 22: Electromechanical tensile test method for conductive thin films on
flexible substrates**

**Dispositifs à semiconducteurs – Dispositifs microélectromécaniques –
Partie 22: Méthode d'essai de traction électromécanique pour les couches
minces conductrices sur des substrats souples**





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CONTENTS

FOREWORD.....	3
1 Scope.....	5
2 Normative references	5
3 Terms, definitions, symbols and designations	5
3.1 Terms and definitions.....	5
3.2 Symbols and designations	6
4 Test piece	6
4.1 General.....	6
4.2 Shape of a test piece	6
4.3 Measurement of dimensions	7
5 Testing method and test apparatus.....	7
5.1 Test principle	7
5.2 Test machine	7
5.3 Test procedure.....	9
5.4 Test environment	9
6 Test report.....	9
Figure 1 – Bilayered test piece.....	6
Figure 2 – Schematic of an electromechanical test machine	8
Figure 3 – Electromechanical tensile grip.....	9
Table 1 – Symbols and designations of a test piece	6

INTERNATIONAL ELECTROTECHNICAL COMMISSION

SEMICONDUCTOR DEVICES –
MICRO-ELECTROMECHANICAL DEVICES –

**Part 22: Electromechanical tensile test method
for conductive thin films on flexible substrates**

FOREWORD

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International Standard IEC 62047-22 has been prepared by subcommittee 47F: Micro-electromechanical systems, of IEC technical committee 47: Semiconductor devices.

The text of this standard is based on the following documents:

FDIS	Report on voting
47F/186/FDIS	47F/190/RVD

Full information on the voting for the approval of this standard can be found in the report on voting indicated in the above table.

This publication has been drafted in accordance with the ISO/IEC Directives, Part 2.

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SEMICONDUCTOR DEVICES – MICRO-ELECTROMECHANICAL DEVICES –

Part 22: Electromechanical tensile test method for conductive thin films on flexible substrates

1 Scope

This part of IEC 62047 specifies a tensile test method to measure electromechanical properties of conductive thin micro-electromechanical systems (MEMS) materials bonded on non-conductive flexible substrates. Conductive thin-film structures on flexible substrates are extensively utilized in MEMS, consumer products, and flexible electronics. The electrical behaviours of films on flexible substrates differ from those of freestanding films and substrates due to their interfacial interactions. Different combinations of flexible substrates and thin films often lead to various influences on the test results depending on the test conditions and the interfacial adhesion. The desired thickness of a thin MEMS material is 50 times thinner than that of the flexible substrate, whereas all other dimensions are similar to each other.

2 Normative references

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IEC 62047-2:2006, *Semiconductor devices – Micro-electromechanical devices – Part 2: Tensile testing method of thin film materials*

IEC 62047-3:2006, *Semiconductor devices – Micro-electromechanical devices – Part 3: Thin film standard test piece for tensile testing*

IEC 62047-8:2011, *Semiconductor devices – Micro-electromechanical devices – Part 8: Strip bending test method for tensile property measurement of thin films*

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